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U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. 690121.407USPC	APPLICATION NO.
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)	APPLICANTS Takayuki Shima et al.	
	FILING DATE December 1, 2004	GROUP ART UNIT

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA					
	AB					
	AC					
	AD					
	AE					

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO
AF	04298389	10/22/92	JP (+Abstract)	
AG	2004087073	03/18/04	JP (+Abstract)	
AH	06262854	09/20/94	JP (+Abstract)	
AI	2005-025841	01/27/05	JP (+Abstract)	

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

AJ	Extended Abstracts (The 63 rd Meeting); The Japan Society of Applied Physics, P1005
AK	Kikukawa, T. et al., "Rigid bubble pit formation and huge signal enhancement in super-resolution near-field structure disk with platinum-oxide layer", Applied Physics Letters, Vol. 81, December 16, 2002, pgs. 4697-4699
AL	Shima, T. et al., "Optical and Structural Property Change by the Thermal Decomposition of Amorphous Platinum Oxide Film", Japanese Journal of Applied Physics, Vol. 42, June 2003, pg. 3479-3480
AM	Kim, J. et al., "Super-resolution by elliptical bubble formation with PtO _x and AgInSbTe layers", Applied Physics Letters, Vol. 83, September 1, 2003, pgs. 1701-1703
AN	Kim, J. et al., "Signal Characteristics of Super-RENS Disk at Blue Laser System", Fr-J-01 (Invited), pgs. 264-265
AO	Kim, J. et al., "Random Pattern Signal Characteristics of Super-RENS Disk at Blue Laser System", Optical Society of America, 2004, pgs. 273-275

EXAMINER /Anna Verderame/	DATE CONSIDERED 08/26/2008
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* EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).